



PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Tetsuo TANIGUCHI et al.

Group Art Unit: 2877

Application No.: 09/593,800

Examiner: P. Natividad

Filed: June 15, 2000

Docket No.: 106514

For: STAGE DEVICE AND EXPOSURE APPARATUS

12/19/01
24.

C

G. Staley
4-12-02

AMENDMENT

Director of the U.S. Patent and Trademark Office
Washington, D.C. 20231

Sir:

In reply to the Office Action dated December 6, 2001, the shortened statutory period for reply being extended by the attached Petition for Extension of Time, please amend the above-identified application as follows:

IN THE CLAIMS:

Please replace claim 10 as follows:

10. (Amended) A stage device comprising a movable stage that is movable at a predetermined degree of freedom;
an interferometer system which measures an amount of displacement of the movable stage by directing a measurement light at the movable stage and causing a reflected light thereof to interfere with a reference light, wherein the interferometer system has a plurality of measurement axes of the measurement light and is disposed such that even if one of the plurality of measurement axes is not irradiating the movable stage, the amount of displacement can still be measured by another measurement axis; and

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